## What is Claimed Is:

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- 1. A method of manufacturing a magnetic recording medium, comprising sequential steps of:
  - (a) providing an apparatus for manufacturing said medium;
  - (b) supplying said apparatus with a substrate for said medium;
- (c) forming a magnetic recording layer on said substrate in a first portion of said apparatus;
  - (d) treating said magnetic recording layer with oxygen gas in a second portion of said apparatus at a sub-atmospheric pressure and for an interval sufficient to provide the resultant medium with at least one of the following, relative to a similar medium manufactured by a similar method but wherein the oxygen treatment of step (d) is not performed:
    - (i) a more negative nucleation field  $(H_n)$ ;
    - . (ii) increased remanent squareness  $(S_r)$ ;
      - (iii) increased signal-to-medium noise ratio (SMNR);
      - (iv) narrower switching field distribution (SFD); and
      - (v) decreased thermal decay rate; and
  - (e) forming a protective overcoat layer on said oxygen-treated magnetic recording layer in a third portion of said apparatus.
    - 2. The method according to claim 1, wherein:
  - step (a) comprises providing an apparatus including at least said first, second, and third spaced-apart portions.
    - 3. The method according to claim 2, wherein:
  - step (a) comprises providing an apparatus adapted for continuous manufacture of a plurality of media and including means for transporting said substrate serially through said first, second, and third spaced-apart portions.

- 4. The method according to claim 3, wherein said first, second, and third spaced-apart, serially arranged portions of said apparatus respectively comprise first, second, and third spaced-apart chambers and at least said second chamber is adapted for providing a sub-atmospheric pressure therein.
- 5. The method according to claim 4, wherein said second chamber comprises means for flowing a mixture of oxygen gas diluted with an inert carrier gas past a surface of said magnetic recording layer formed on said substrate in step (c).
- 6. The method according to claim 4, wherein said first and third chambers of said apparatus are adapted for performing a thin film deposition process therein.
- 7. The method according to claim 6, wherein at least said first chamber of said apparatus is adapted for performing a sputtering process therein.
  - 8. The method according to claim 1, wherein:
- step (c) comprises forming a magnetic recording layer selected from the group consisting of: (1) a Co-based alloy, Cr-rich grain boundary type magnetic layer; (2) a granular type magnetic layer; (3) a superlattice-type layer; and (4) an L1<sub>0</sub> ferromagnetic metal alloy type layer.
  - 9. The method according to claim 8, wherein:
- step (c) comprises forming a Co-based alloy, Cr-rich grain boundary type magnetic recording layer comprised of a CoCrPtX alloy, where X = at least one element selected from the group consisting of Ta, B, Mo, V, Nb, W, Zr, Re, Ru, Cu, Ag, Hf, Ir, and Y, and wherein Co-containing grains with *hcp* lattice structure are segregated by Cr-rich grain boundaries.

10. The method according to claim 9, wherein:

step (d) comprises treating said magnetic recording layer with a gas mixture comprising up to about 20 % oxygen gas in at least one inert diluent gas, at a total gas pressure up to about 50 mTorr, and for an interval up to about 10 sec.

## 11. The method according to claim 10, wherein:

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step (c) further comprises utilizing a heated substrate during formation of said magnetic recording layer to effect segregation of Cr in said grain boundaries.

12. A perpendicular magnetic recording medium manufactured by the method according to claim 11.

# 13. The method according to claim 8, wherein:

step (c) comprises forming a granular-type magnetic recording layer comprised of a CoPtX alloy, where X = at least one material selected from the group consisting of Cr, Ta, B, Mo, V, Nb, W, Zr, Re, Ru, Cu, Ag, Hf, Ir, Y, SiO<sub>2</sub>, SiO, Si<sub>3</sub>N<sub>4</sub>, Al<sub>2</sub>O<sub>3</sub>, AlN, TiO, TiO<sub>2</sub>, TiO<sub>x</sub>, TiN, TiC, Ta<sub>2</sub>O<sub>3</sub>, NiO, and CoO, and wherein Co-containing grains with *hcp* lattice structure are segregated by oxide, nitride, or carbide grain boundaries.

## 14. The method according to claim 13, wherein:

step (d) comprises treating said magnetic recording layer with a gas mixture comprising up to about 20 % oxygen gas in at least one inert diluent gas, at a total gas pressure up to about 50 mTorr, and for an interval up to about 10 sec.

## 15. The method according to claim 14, wherein:

step (d) comprises treating said magnetic recording layer with oxygen gas without applying heat thereto.

- 16. A perpendicular magnetic recording medium manufactured by the method according to claim 15.
  - 17. The method according to claim 8, wherein:
- step (c) comprises forming a superlattice-type magnetic recording layer comprising a multi-layer  $(CoX/Pd)_n$  or  $(CoX/Pt)_n$  structure, where n is an integer from about 10 to about 25 and X is an element selected from the group consisting of Cr, Ta, B, Mo, Pt, W, and Fe; and
- step (d) comprises treating said magnetic recording layer with oxygen gas without applying heat thereto.
- 18. A perpendicular magnetic recording medium manufactured by the method according to claim 17.
  - 19. The method according to claim 8, wherein:
- step (c) comprises forming an L1<sub>0</sub> ferromagnetic metal alloy-type layer comprising a FePt or CoPt alloy.
- 20. A perpendicular magnetic recording medium manufactured by the method according to claim 19.
  - 21. The method according to claim 1, wherein:
- step (b) comprises supplying said apparatus with a disk-shaped substrate for a hard disk magnetic recording medium.
- 22. A disk drive comprising a magnetic recording medium formed by the process according to claim 21.
  - 23. The method according to claim 1, wherein:
- step (e) comprises forming a carbon-based protective overcoat layer on said oxygen-treated magnetic recording layer.

- 24. A method of manufacturing magnetic recording media according to a continuous process, comprising sequential steps of:
  - (a) providing at least one substrate for said magnetic recording media;
- (b) providing an apparatus adapted for continuous manufacturing of said magnetic recording media, comprising at least first, second, and third spaced-apart, serially arranged processing chambers and including means for transporting said at least one substrate serially through at least said first, second, and third spaced-apart processing chambers;
- (c) transporting said substrate through said first processing chamber while forming a magnetic recording layer thereon;

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- (d) transporting said substrate with said magnetic recording layer formed thereon to said second processing chamber;
- (e) transporting said substrate through said second processing chamber while treating said magnetic recording layer with oxygen gas at a sub-atmospheric pressure and for an interval sufficient to provide the resultant media with at least one of the following, relative to similar media manufactured by a similar method but wherein the oxygen treatment of step (e) is not performed:
  - (i) a more negative nucleation field  $(H_n)$ ;
  - (ii) increased remanent squareness (S<sub>r</sub>);
  - (iii) increased signal-to-medium noise ratio (SMNR);
  - (iv) narrower switching field distribution (SFD); and
  - (v) decreased thermal decay rate;
- 20 (f) transporting said substrate with said oxygen-treated magnetic recording layer formed thereon to said third processing chamber; and
  - (g) transporting said substrate through said third processing chamber while forming a protective overcoat layer on said oxygen-treated magnetic recording layer; wherein:
- said substrate is transported between and through each of said first, second, and third processing chambers at a substantially constant rate.

- 25. The method according to claim 24, wherein:
- step (a) comprises providing at least one disk-shaped substrate for hard disk magnetic recording media;
- step (b) comprises providing an apparatus wherein said first and third chambers are adapted for performing a thin film deposition process therein and at least said second chamber is adapted for providing a sub-atmospheric pressure therein; and
- step (c) comprises forming a magnetic recording layer selected from the group consisting of: (1) a Co-based alloy, Cr-rich grain boundary type magnetic layer; (2) a granular type magnetic layer; (3) a superlattice-type layer; and (4) an L1<sub>0</sub> ferromagnetic metal alloy type layer.